

Page 11, please replace the second paragraph with the following new paragraph:

C3
A running system (film formation means) runs at a constant speed, a base 3a from the feed roll 4 to the winding roll 6 by way of the guide rolls 5a, 5b, 5c, 5d, and 5f. The plasma electrode 8, which is used for preparation such as degassing of the base 3a, is opposed to a portion, disposed between the guide rolls 5a and 5b, of the base 3a. The evaporation sources 7a and 7b, each of which is configured typically as a sputtering system, are disposed with their targets opposed to the guide roll 5d. The target is made from Si, Nb or the like as an optical thin layer material.

Page 13, please replace the third paragraph, continuing to page 14, with the following new paragraph:

C4
The optical head 10g has a light emitting unit 12 and a light receiving unit 13. The light emitting unit 12 is a light source enabling continuous emission of light having a wavelength of 450 to 700 nm, that is, a light source having a continuous spectrum of 450 to 700 nm in wavelength. The light emitting unit 12 is configured as an LED (Light Emitting Device). The light receiving unit 13 is configured as a photodiode for detecting a continuous spectrum of 450 to 700 nm in wavelength. The light emitting unit 12 and the light receiving unit 13 are opposed to each other with the running base 3a put therebetween. The light emitting unit 12 is connected to the light source 10c. The light source 10c, in principle, supplies a specific quality of light. An optical communication line 10b extending from the switch 10f is connected to a mid point of the communication line between the light emitting unit 12 and the light source 10c.

IN THE CLAIMS:

Please enter the following amended claims:

- C5 sub 1
9. (Amended) An optical component producing method for forming a multi-layer film, which is